

Sensitivity analysis and tolerancing of Mid Wave IR metalenses

Lieven Penninck, Wouter Woestenborghs

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Who are we?

- ❖ Start-up from Ghent, Belgium
- ❖ Dedicated provider of:
 - **Simulation** software for **metasurfaces**
 - **Designhouse** for photonic & optical applications
- ❖ 20 years of photonics R&D experience in industry and academia:
 - Simulation
 - Fabrication
 - Measurement
- ❖ Supported by:



Founding team

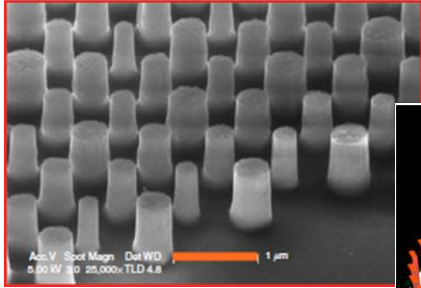


Dr. Lieven
Penninck

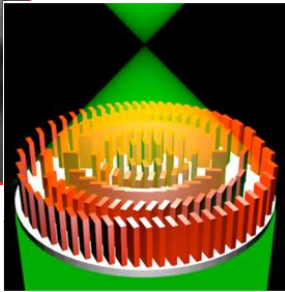


Dr. Wouter
Woestenborghs

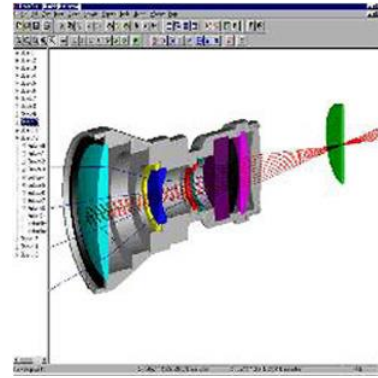
Nano-scale design



Component design



System Integration



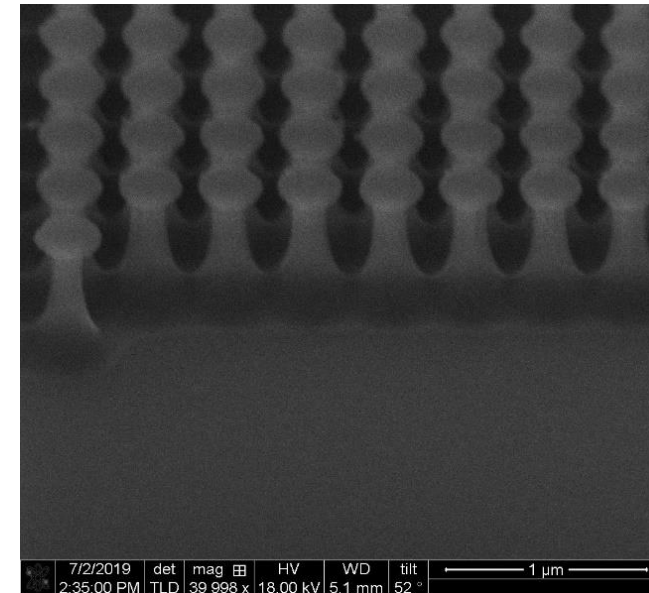
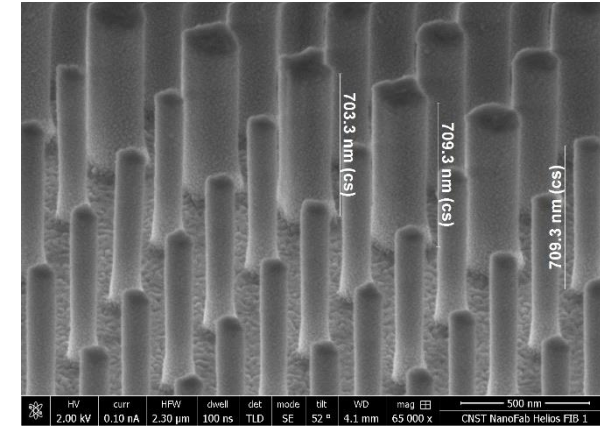
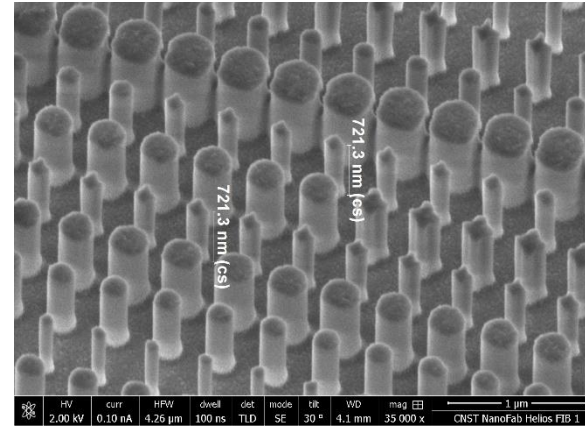
Planopsim's mission
Planopsim supplies R&D tools to engineers & scientists that allow to unlock the maximum benefit of flat optics in a user-friendly way.



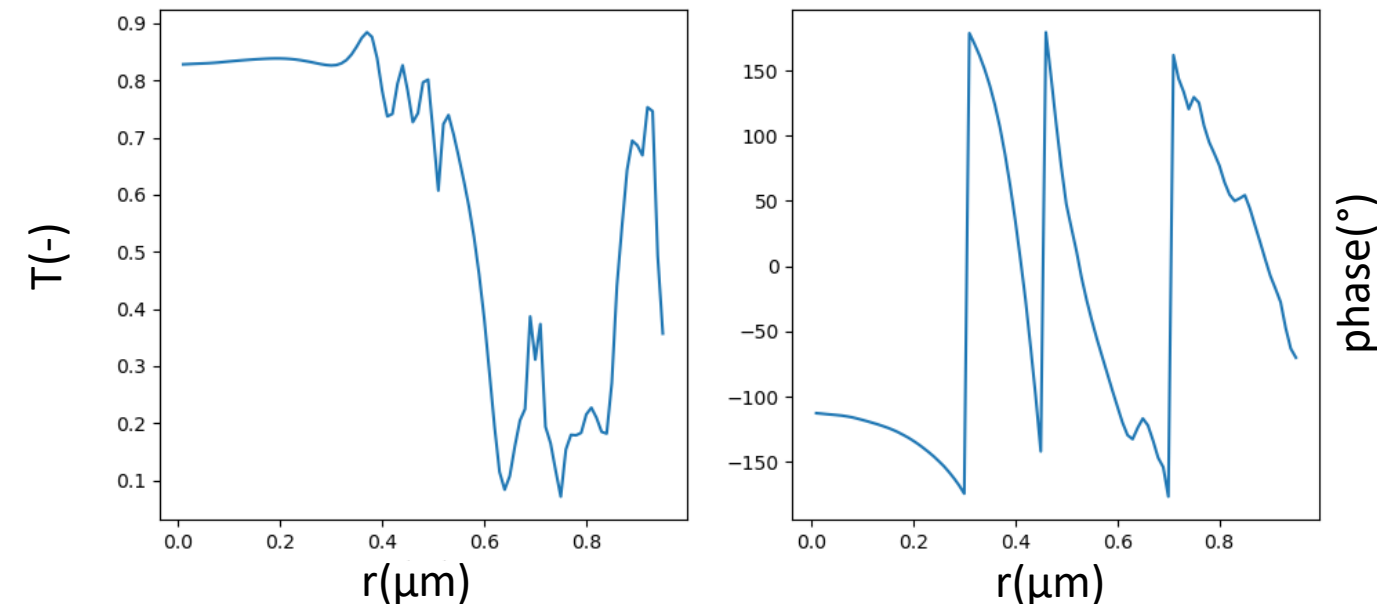
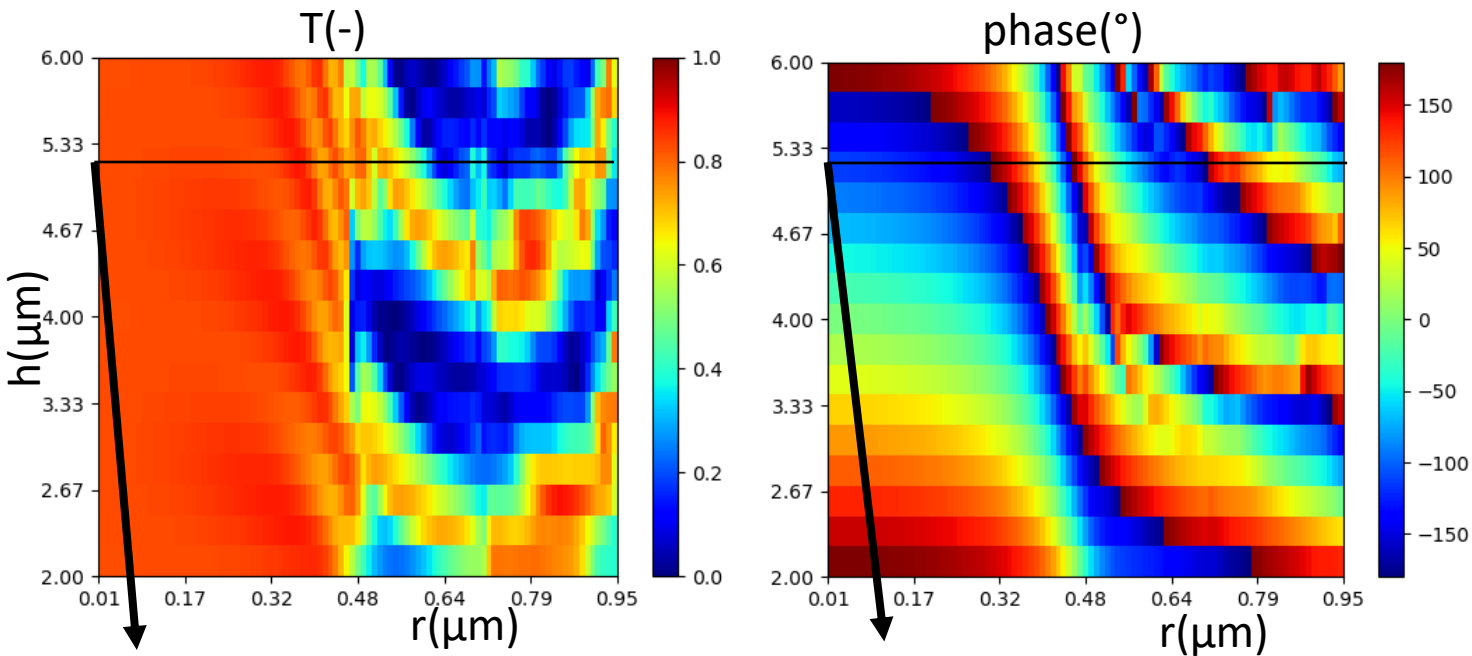
- ❖ Computer Aided Design **software for Planar Optics & metasurfaces**
 - All-in-one design workflow
- ❖ **Design service** for metasurfaces and photonics
 - In-house and 3^d party tools

Which errors are critical?

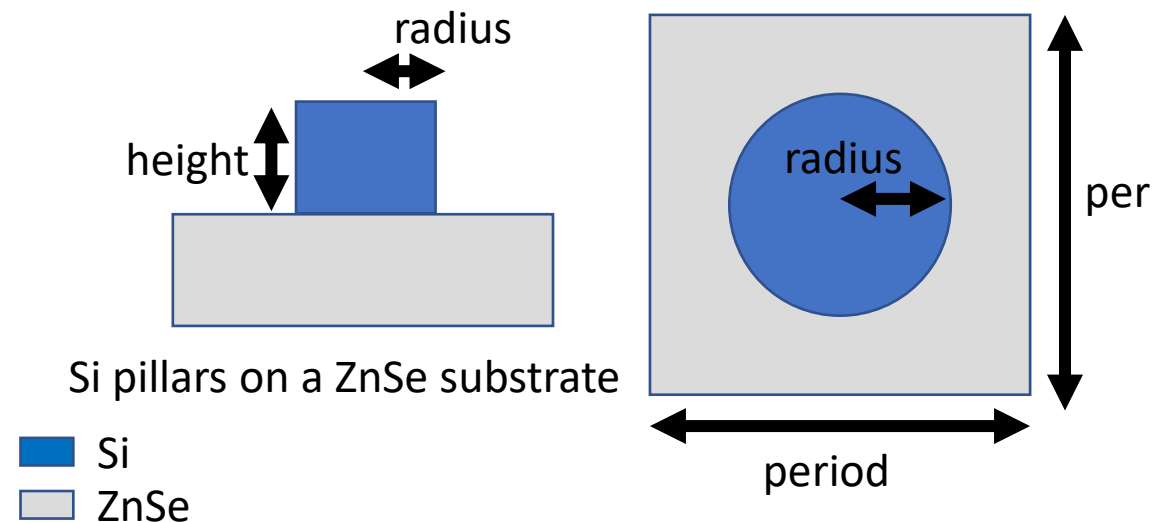
- ❖ Typical design assumption:
 - All structures are perfect
 - Optimize until specifaction is reached
- ❖ **X Million structures** in 1 meta-surface component
- ❖ There are systematic & random errors
 - This study: **systematic errors**
 - Random errors: Monte Carlo analysis
- ❖ In practice:
 - Which errors are critical-to-quality?
 - What is the effect of various error types
 - Which deviation can be tolerated of each type
- ❖ Sensitivity analysis:
 - Design using nominal structures
 - Simulation replaces nominal by perturbed structures



Reference meta-atom



- ❖ Meta-atom type:
 - Design λ : $4 \mu\text{m}$
 - a-Si Cylindrical pillars on ZnSe
 - Square arrangement
- ❖ Configurations scanned with full Maxwell solver (PlanOpSim MetaCell)
- ❖ 8 meta-atoms selected for $0-360^\circ$ phase coverage
 - P: $2 \mu\text{m}$
 - H: $5, 25 \mu\text{m}$



❖ Reference lens parameters:

- Size: 10 x 10 mm
- Focal distance f : 20 mm
- Corresponding NA: 0.24

❖ Analytical spherical phasefront:

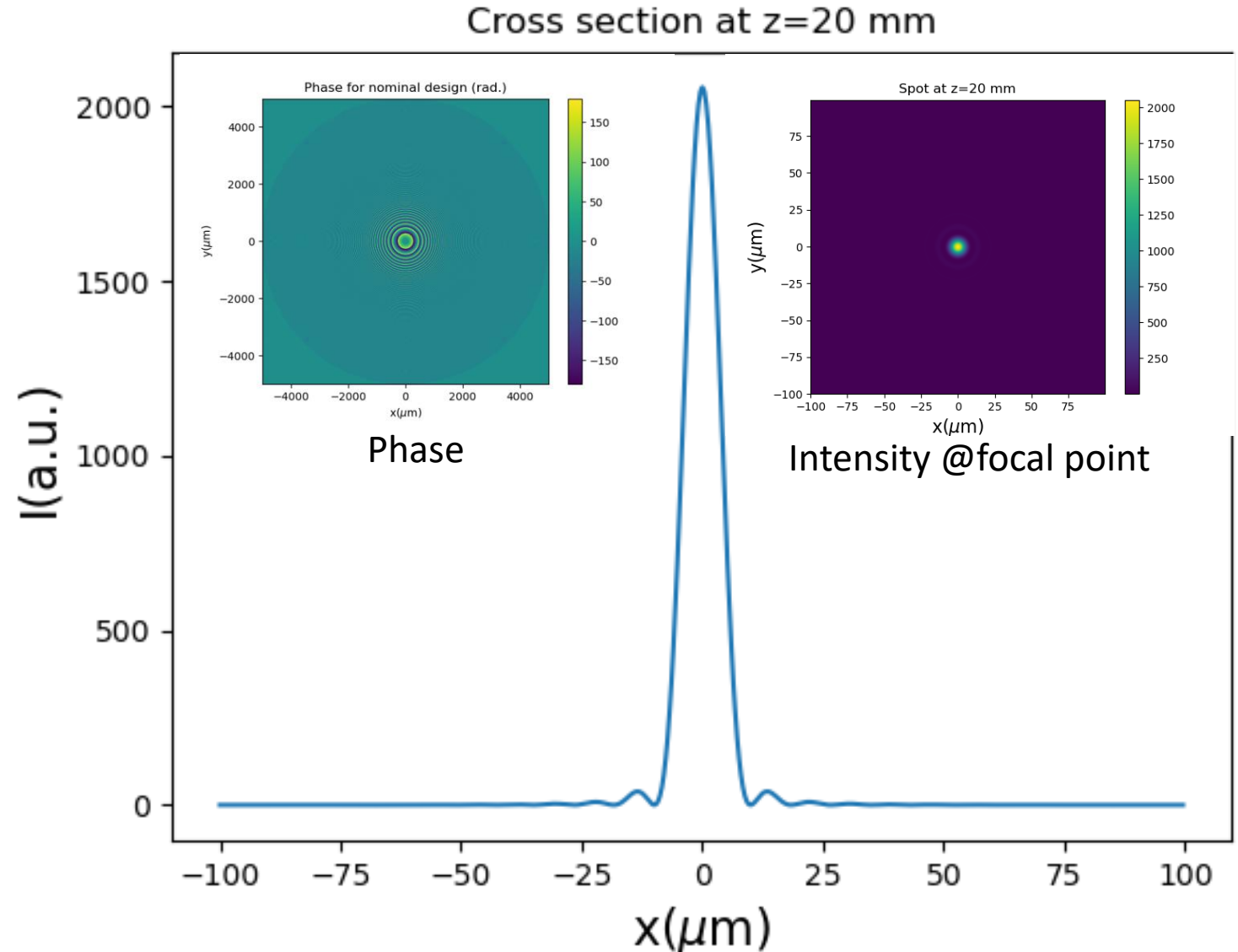
$$\varphi(\lambda) = \frac{2\pi}{\lambda} \left[\sqrt{x^2 + y^2 + f^2} - f \right]$$

❖ Simulated using:

- Fresnel propagation
- Local periodic approximation
- PlanOpSim Meta-Component

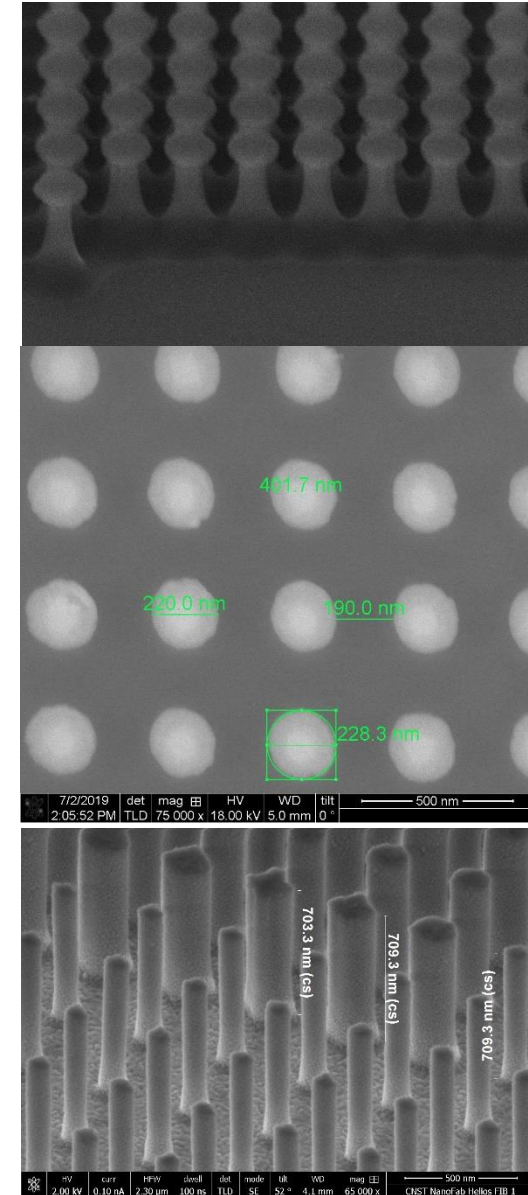
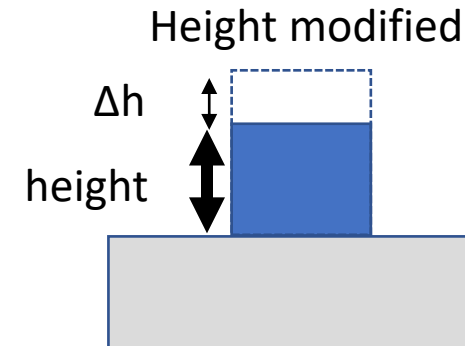
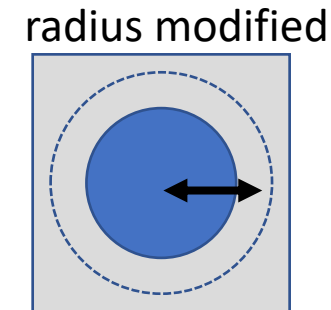
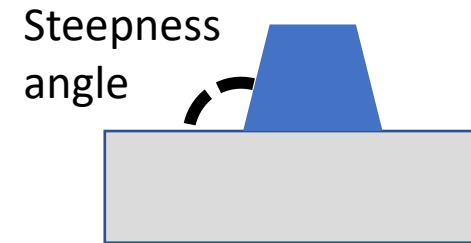
❖ Nominal spot characteristics:

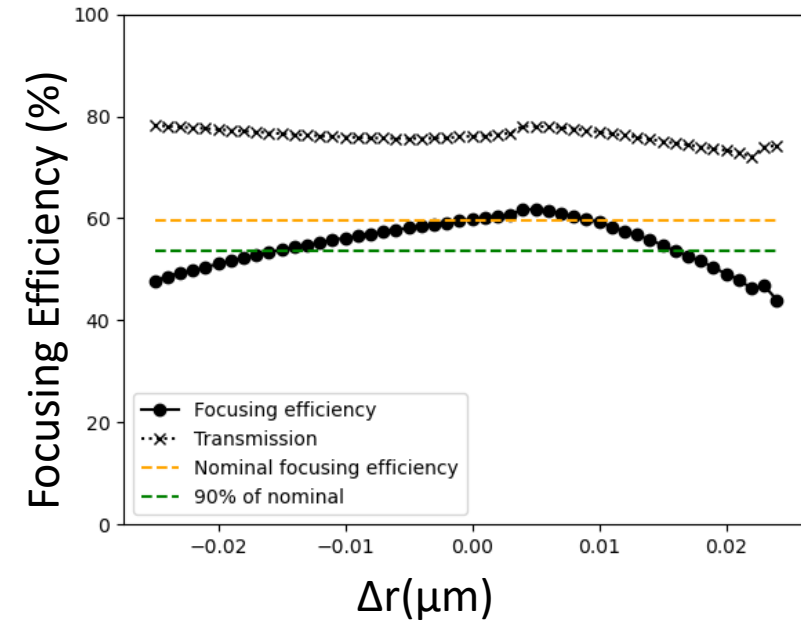
- FWHM: 8.43 μm
- Transmission efficiency: 76.0%
- Focussing efficiency: 59%



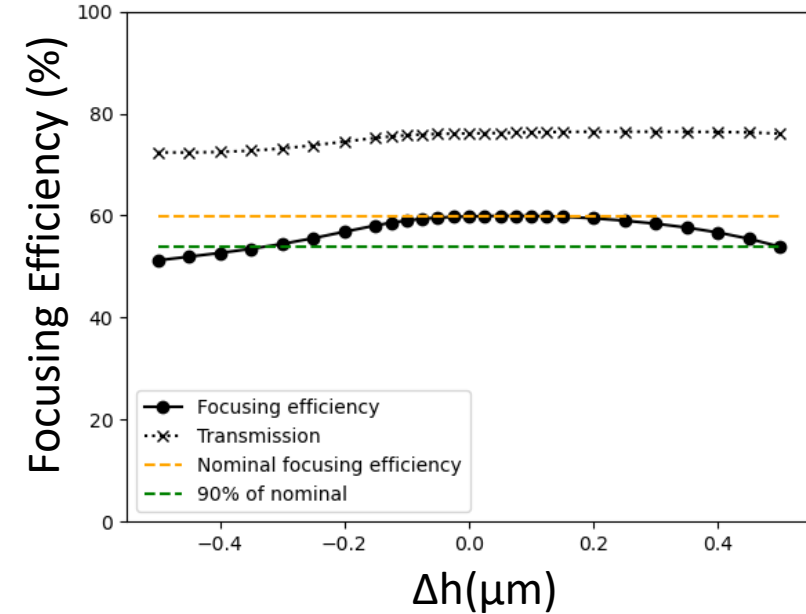
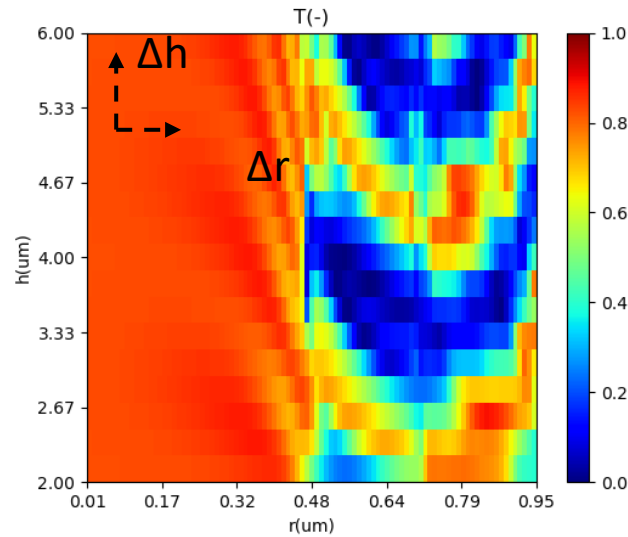
Error types

- ❖ Meta-atoms **uniformly modified from nominal** design parameters over entire meta-lens
- ❖ Sidewall angle
 - Nominally 90°
 - Varied parameter: angle
 - Assumption: cylinder \rightarrow cone
 - Over- and underetching common
- ❖ Direct radius deformation
 - Varied parameter: Δr
 - Differences in resist exposure/developing
- ❖ Height difference
 - Varied parameter: Δh
 - Variations in film evaporation
- ❖ There are many more!

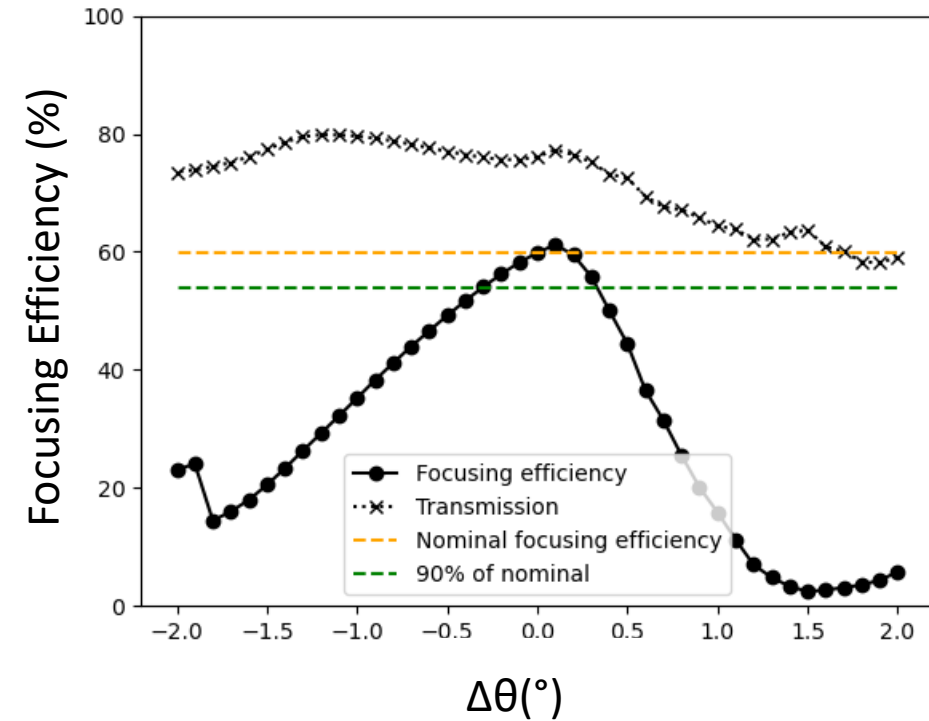




- ❖ $\Delta r = \pm 0,025 \mu\text{m}$
- ❖ Transmission 76- \rightarrow 72%
- ❖ Focussing efficiency 59,9- \rightarrow 44,0%
- ❖ Threshold 90% of nominal focussing efficiency:
 - $\pm 15\text{nm}$
 - 0,75% of pitch/ 0,375% λ

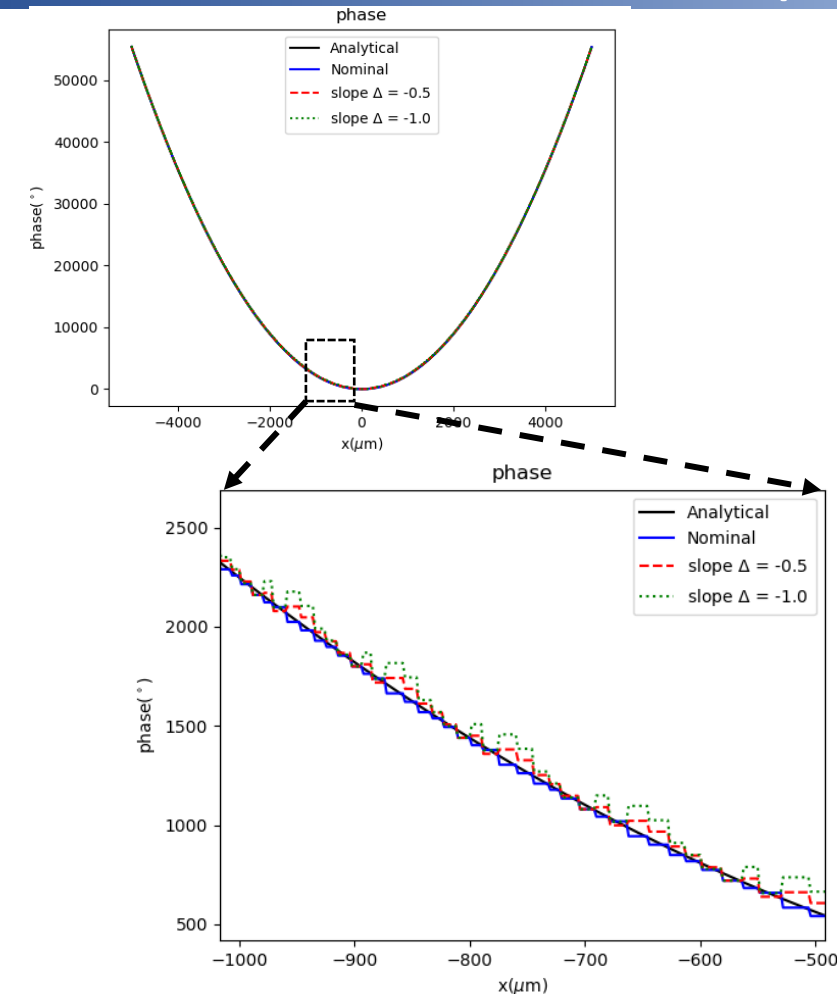


- ❖ $\Delta h = \pm 0,50 \mu\text{m}$
- ❖ Transmission 76- \rightarrow 72,3%
- ❖ Focussing efficiency 59,9- \rightarrow 51,2%
- ❖ Threshold 90% of nominal focussing efficiency:
 - -300nm+500nm
 - -5,7/+9,5% of height
 - -7,5% / 12,5% λ

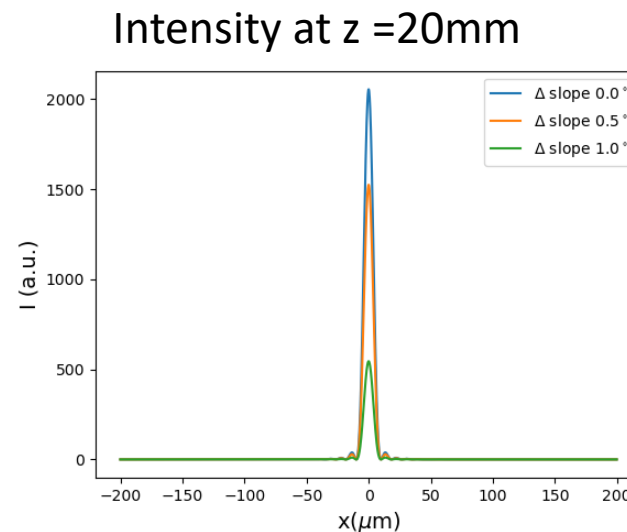


- ❖ $\Delta\theta = \pm 2^\circ$
- ❖ Most sensitive parameter
- ❖ Transmission 76 \rightarrow 58.2%
- ❖ Focussing efficiency 59,9 \rightarrow 2.4%
- ❖ Focussing reduces more quickly than transmission
- ❖ Threshold 90% of nominal focussing efficiency:
 - $\pm 0,3^\circ$

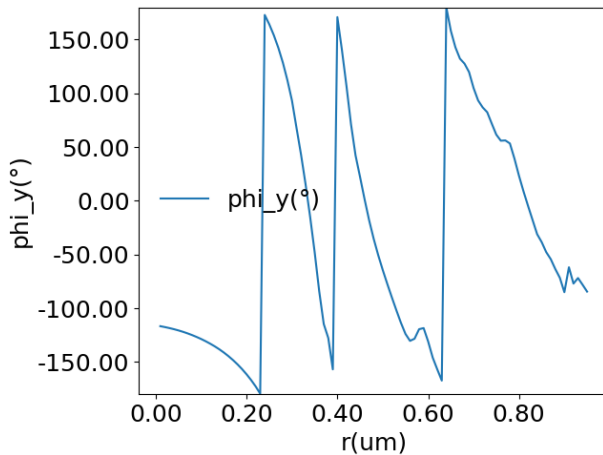
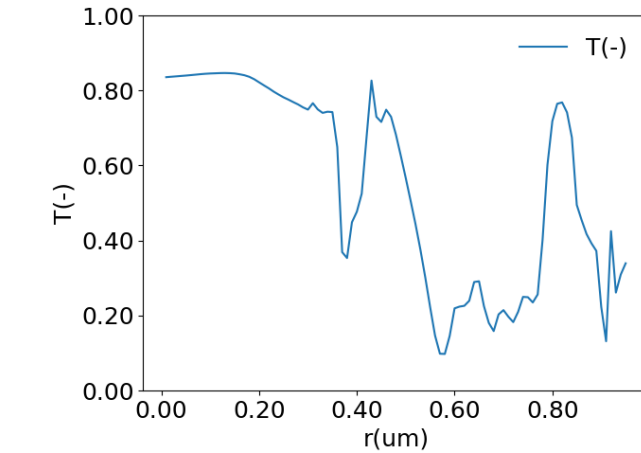
What causes the performance loss



- ❖ Wavefront phase for nominal and aberrated cases
 - Example: sidewall angle
- ❖ Overall wavefront shape remains the same
- ❖ Aberrated wavefront -> perturbation on ideal wavefront
 - Focal distance remains the same
 - Spot width remains the same
 - Loss of efficiency to scattering
- ❖ Transmission: additional loss



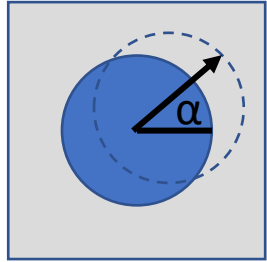
Sidewall angle	Phase error (RMS)	Amplitude error (RMS)
90° (nominal)	16,2°	0,19
89,5°	34,2°	0,23
89°	68,5°	0,35



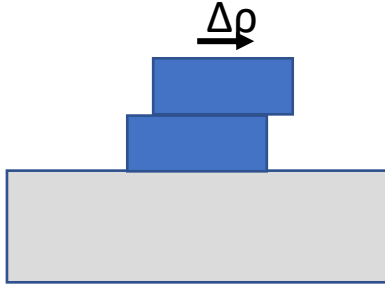
- ❖ Known sidewall steepness $88,5^{\circ}$ (worst case)
- ❖ Meta-atoms resimulated and selected
 - $P = 2\mu\text{m}$
 - $H = 5,25\mu\text{m}$
- ❖ Meta-atoms placement repeated using new meta-atom results
- ❖ **A known and constant error can be compensated**

Sidewall angle	Transmission	Focussing efficiency	F/T
90° (nominal)	76%	59.9%	0,76
88,5° (uncompensated)	63,7%	2,4%	0,04
88,5° (compensated)	76,7%	60,9%	0,79

Top view

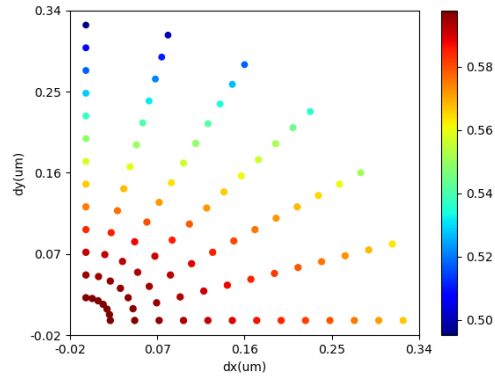


Side view

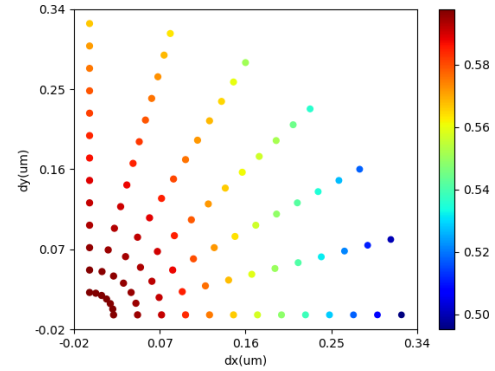


- ❖ Multi-layer structures
 - Reference case 2-layers
- ❖ Alignment error:
 - Angle α (0-90°)
 - Distance ρ (0-325nm)
- ❖ Average focussing independent of angle
 - Causes polarization sensitivity
- ❖ Focusing efficiency 59.9->53,1%
 - Transmission 76% -> 70,1%
 - Efficiency mostly lost through reduced transmission

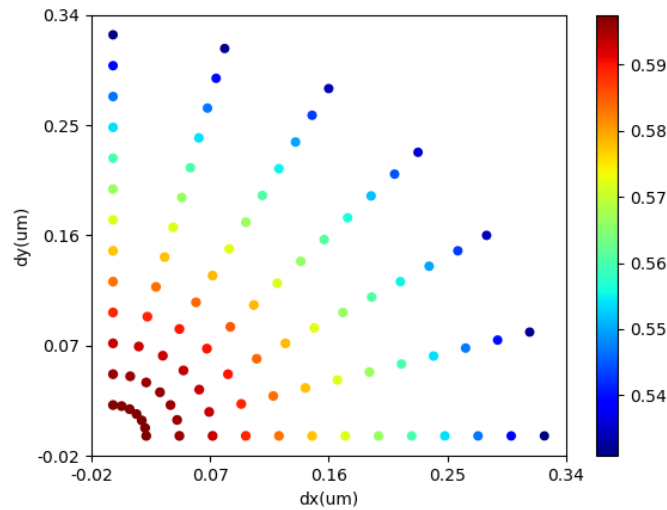
TE



TM

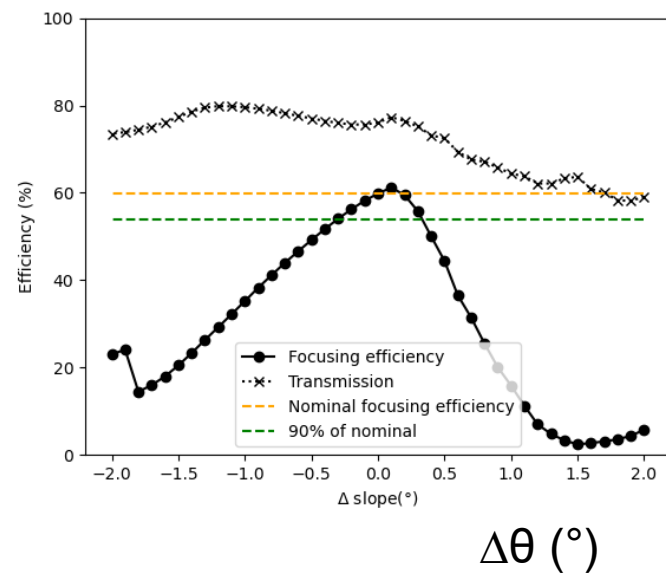


Focussing Efficiency

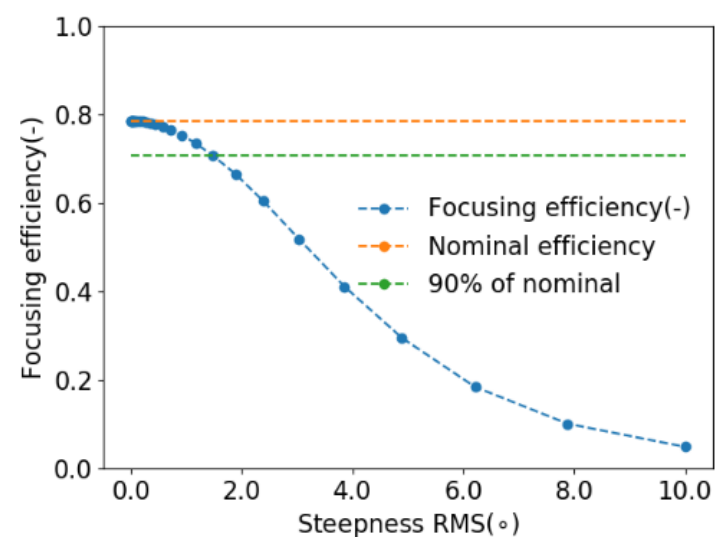


Comparison systematic to random error

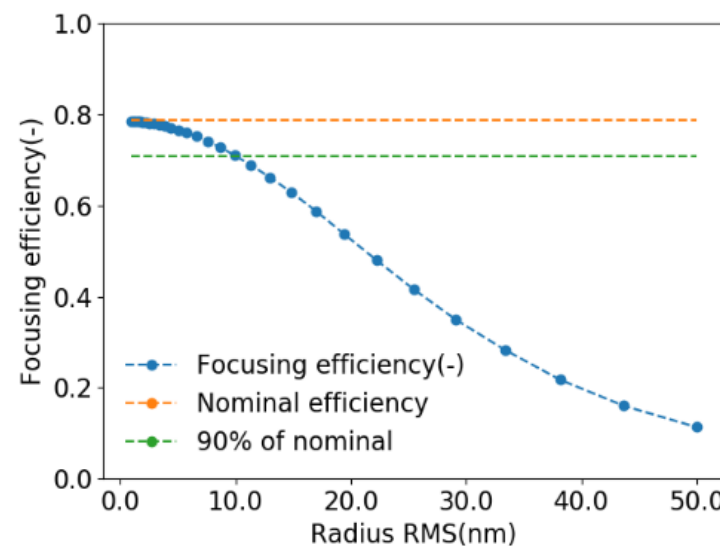
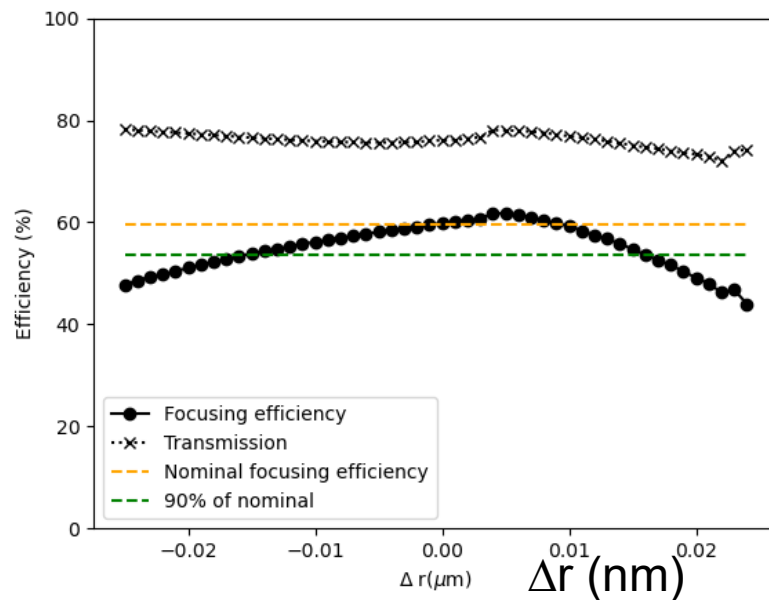
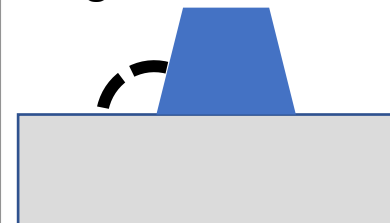
Systematic errors



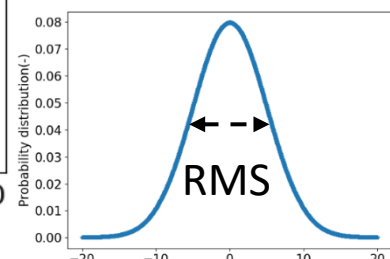
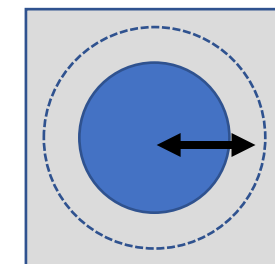
Random errors (Monte Carlo)



Steepness
angle



radius modified



- ❖ **Systematic errors have a stronger impact than random errors on focussing efficiency**
- ❖ **Monte carlo results for meta-lens for 532nm**

- ❖ **Knowing and controlling critical parameters** is crucial
- ❖ **Sensitivity analysis** used to **identify** critical parameters and **quantify tolerance criteria**
- ❖ Fast integrated **simulations** provide insight to the **link** between structural **parameters** and device **performance**
- ❖ **Wavefront aberration** is the main cause of efficiency loss
- ❖ Fabrication guidelines (for reference metalens)

Parameter	Tolerance for 90% of nominal efficiency
Sidewall slope	$\pm 0,3^\circ$
Radius	$\pm 15\text{nm}$ (0,75% of pitch)
Height	$-300\text{nm}/+500\text{nm}$ (5,7/9,5% of height)

Reach us here!



www.planopsim.com



lieven.penninck@planopsim.com



+32 485 56 57 72

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